

Contents

Acknowledgement	vii
1 Introduction	1
2 Basics of MEMS capacitive inertial sensors	9
2.1 Working principle of MEMS inertial sensors	9
2.1.1 Acceleration sensors	10
2.1.2 Angular rate sensors	10
2.1.3 Multi-functional / axis sensors	11
2.2 Fabrication of MEMS inertial sensors	12
2.2.1 Fabrication of the functional wafer	12
2.2.2 Fabrication of the encapsulation wafer	14
2.2.3 Fabrication of the stack	14
2.3 Mechanisms influencing the cavity pressure	17
3 Microchip calibration for cavity pressure estimation	19
3.1 Methods for cavity pressure estimation	19
3.2 Damped oscillatory motion	20
3.2.1 Quality factor and gas damping	23
3.3 Measurements	26
3.3.1 Experimental setup	26
3.3.2 Results and discussion	27
3.4 Summary	29
4 Hydrogen release from PECVD thin films	31
4.1 Background to hydrogen in CVD dielectrics	31
4.2 Methods for material characterization	33
4.2.1 Inert Gas Fusion	33
4.2.2 Fourier Transform Infrared Spectroscopy	33
4.2.3 Temperature desorption spectroscopy	35
4.3 Materials and experiments	36
4.4 Results	37
4.4.1 Inert Gas Fusion	37
4.4.2 Fourier Transform Infrared Spectroscopy	38
4.4.3 Temperature desorption spectroscopy	41
4.4.4 Discussion	45
4.5 Material modelling and simulation	48
4.5.1 Single reaction model	48
4.5.2 Multi-reaction model	51
4.5.3 Estimation of reaction parameters	53
4.5.4 Diffusion in thick films	57

4.6	Application of models to use cases	60
4.6.1	Hydrogen release during wafer bonding	60
4.6.2	Hydrogen release from dielectric stack	62
4.7	Summary	66
5	Hydrogen release in microchip cavities	67
5.1	Microchip variants and experiments	67
5.2	Results of cavity pressure in microchips	70
5.2.1	Microchips with a single PECVD layer	70
5.2.2	Microchips with PECVD dielectric stack	75
5.3	Discussion and proposed mechanisms	77
5.3.1	Cavity pressure in the absence of PECVD materials	77
5.3.2	Influence of a single PECVD thin film	78
5.3.3	Influence of PECVD dielectric stack	82
5.4	Summary	87
6	Summary and Outlook	89
	Appendix	93
A	Additional Figures	93
B	Additional Tables	95
C	ATR FT-IR depth of penetration	96
	References	96